



35.C13974

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PATENT APPLICATION

TECHNOLOGY CENTER 2800

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
: Examiner: D. Monbleau  
TADAHIRO OHMI, ET AL. )  
: Group Art Unit: 2881  
Application No.: 09/425,015 )  
: Filed: October 25, 1999 )  
: For: GAS SUPPLY PATH )  
STRUCTURE, GAS SUPPLY :  
METHOD, LASER OSCILLATING )  
APPARATUS, EXPOSURE :  
APPARATUS, AND DEVICE )  
PRODUCTION METHOD : October 31, 2001

Commissioner for Patents  
Washington, D.C. 20231

RESPONSE TO RESTRICTION REQUIREMENT

Sir:

This paper is filed in response to the Restriction Requirement dated  
September 7, 2001, requiring Applicants to elect one of the following groups of claims:

Group I: Group I (Claims 1-40), directed to a laser oscillating apparatus;  
and

Group II: Group II (Claims 41-44), directed to an exposure apparatus.